

# Free-standing self-assembled monolayered nanoparticle membranes and their electromechanical properties by conducting AFM

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## Abstract

Freestanding membranes of dodecanethiol coated 7nm colloidal Au nanoparticles assembled at the liquid/liquid interface [1, 2], are deposited over micrometric holes etched in  $\text{Si}_3\text{N}_4$  substrate and addressed by gold electrodes using stencil lithography (Figure 1a). PFTUNA™ (Peak Force Tunneling AFM) cartography and spectroscopy are performed on these free-standing self-assembled nanoparticle membranes (Figure 2b). Their deformation cartography and mechanical properties are determined from AFM force-displacement curves measured across the entire membrane area. The Young modulus and pre-stress of these free-standing self-assembled nanoparticle membranes are in the range of several GPa and a few tenth of MPa respectively. Force-dependent current spectroscopy measurements are performed to study intrinsic electro-mechanical properties of monolayered nanoparticle membranes in a substrate-free configuration. On increasing the applied load, we observe an increase in the electrical resistance of the membranes as a result of the membrane deformation. To quantify this effect, the membrane deformation measured by AFM is analyzed using finite element modeling. The electrical resistance variation of the membrane as a function of deformation shows high sensitivity value of  $\sim 100$ . These results show that free-standing self-assembled monolayered nanoparticle membranes are potential candidates for ultra-sensitive nanosensor applications.

## References

[1] K.E. Mueggenburg, X.M. Lin, R.H. Goldsmith, and H.M. Jaeger, *Nat Mater*, **9**, 2007, 656–660

[2] J. He, P. Kanjanaboos, N.L. Frazer, A. Weis, X.M. Lin, and H.M. Jaeger, *Small*, **13**, 2010, 1449–1456

## Figure

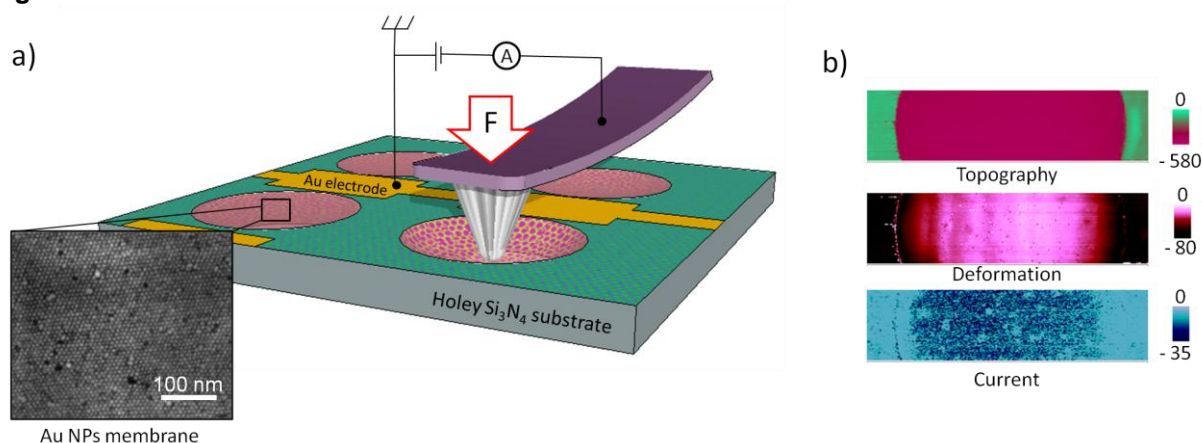


Figure 1: a) Schematic of free-standing self-assembled monolayered nanoparticle membranes deposited on holey  $\text{Si}_3\text{N}_4$  substrate investigated by PFTUNA. Inset shows a scanning electron microscope image of the close-packed nanoparticles in the membrane. b) Typical topography, deformation and current images in PFTUNA mode of a same membrane at a fixed force setpoint of 9 nN and applied voltage of 0.5 V.